



Patent

Attorney Docket No. 8003-398

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application	)	<u>Patent Application</u>
	)	
Inventor(s): Emir Gurer et al.	)	Art Unit: 1763
	)	
Application No: 09/874,073	)	Examiner: Kackar, Ram N.
	)	
Filed: June 4, 2001	)	
	)	
Title: Plasma Deposition of Spin Chucks to Reduce	)	
Contamination of Silicon Wafers	)	
	)	

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TC 1700

Mail Stop Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Introductory Comments:

This Amendment is in response to the Office Action dated December 31, 2002.

Reconsideration is respectfully requested in view of the following amendments and remarks.